

FORM PTO-1449 (Modified)			ATTY. DOCKET NO.	SERIAL NO.
LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT E JC			FIS920030360US1	10/709,406
(MAY 7 2004) (Use several sheets if necessary)			APPLICANT: <b>BRODSKY ET AL.</b>	
MAY 7 2004			FILING DATE:	GROUP:

## REFERENCE DESIGNATION U.S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	ISSUED DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPRO.)

## FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION
						YES NO

## OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

TN	CA	S. Lee et al. "New Approach for Pattern Collapse Problem by Increasing Contact Area at Sub-100nm Patternning," Proc. SPIE – The International Society for Optical Engineering, June 2003, pp. 166-174 (Vol. 5039).

EXAMINER /Thanh Nguyen/ DATE CONSIDERED 06/27/2006

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance \_\_\_\_\_ and not considered. Include copy of this form with next communication to applicant.